

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of:

Scott A. Chalmers, et al.

Appl. Serial No.: 09/899,383

Filed: July 3, 2001

For: METHOD AND APPARATUS FOR HIGH-SPEED THICKNESS MAPPING OF PATTERNED THIN FILMS



Art Unit:

Examiner:

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RECEIVED  
MAR 28 2002  
1C 2800 MAIL ROOM

PRELIMINARY AMENDMENT

Commissioner for Patents  
Washington, D.C. 20231

Sir:

Prior to examination thereof, kindly amend the subject application as follows:

IN THE CLAIMS:

Kindly amend claims 1, 4-6, 23, 24, 26, 35, and 39-41 as follows:

1. (Once Amended) A system for measuring one or more properties of one or more films comprising:

a light source for directing light to the one or more films;

a one-dimensional imaging spectrometer for receiving light reflected from or transmitted through a one dimensional pattern of spatial locations on the one or more films, and determining

CERTIFICATE OF MAILING  
(37 C.F.R. §1.8a)

I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below in an envelope addressed to Commissioner for Patents, Washington, D.C. 20231 with sufficient postage as First Class Mail.

March, 19 2002  
Date of Deposit

Diana Vilkaitis  
Name of Person Mailing Paper

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